



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Alek C. Chen

Application No. 09/502,062

Filed: February 10, 2000

Titled: IN SITU PROXIMITY GAP MONITOR FOR LITHOGRAPHY

Group Art Unit 2877

Examiner: A. H. MERLINO

RESPONSE TO OFFICE ACTION

Mail Stop Non-Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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TECHNOLOGY CENTER 2800

Sir:

In response to the Examiner's nonfinal Office Action mailed February 27, 2003, applicant submits the following amendments for entry and remarks for consideration as indicated below for the above-identified application. This Response is submitted in the Revised Format mentioned in the *Official Gazette* on February 25, 2003.